

DOCKET NO: 278285US0PCT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
MAKOTO ISHIDA, ET AL. : EXAMINER: QUINTO, KEVIN V.
SERIAL NO: 10/549,364 :
FILED: JULY 17, 2006 : GROUP ART UNIT: 2826
FOR: ULTRASONIC SENSOR :
COMPRISING A :
METAL/FERROELECTRIC/METAL/INSUL
ATOR/SEMICONDUCTOR STRUCTURE

AMENDMENT AND REQUEST FOR RECONSIDERATION

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

In response to the Office Action dated April 17, 2008, Applicants respectfully request reconsideration of the above-identified application in view of the following remarks and attached Declaration under 37 C.F.R. § 1.131:

The current Claims are reflected in the listing of claims which begins on page 2 of this paper. No amendments to the claims are made herein.

Remarks/Arguments begin on page 4 of this paper.

2008年 8月18日 16時48分

MADOKA INT'L P.O.

No. 0284 P. 2

Docket No.: 273285US0PCT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:

GROUP: 2826

Makoto ISHIDA, et al.

SERIAL NO: 10/349,364

EXAMINER: Quinio, Kevin V.

FILED: July 17, 2006

FOR: ULTRASONIC SENSOR COMPRISING A
METAL/FERROELECTRIC/METAL/INSULATOR/SEMICONDUCTOR
STRUCTUREDECLARATION UNDER 37 C.F.R. § 1.131COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

Sir:

New comes Keisuke HIRABAYASHI who deposes and states that:

1. I am an inventor of claims 6, 7 and 12-15 of the patent application identified above and an inventor of the subject matter described and claimed therein.

2. Prior to December 27, 2002, I had completed my invention as described and claimed in the above-identified application in Japan, a WTO country, as evidenced by the attached documents:

a) Document 1 is a program of a research report meeting which occurred at National University Corporation TOYOHASHI UNIVERSITY OF TECHNOLOGY, prior to December 27, 2002. The program lists my name as a presenter of a research report.

b) Document 2 is a summary of the report which I presented. The report indicates that an epitaxial Pt (001) film had been successfully deposited on a γ -Al₂O₃ (001)/Si(001) substrate prior to the meeting date.

Each of the dates deleted from the documents is prior to December 27, 2002.